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Docket No.: SON-1745
(PATENT)

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7/15/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Seiichi Fukuda

Application No.: 09/512,336

Group Art Unit: 1765

Filed: February 24, 2000

Examiner: K. Chen

For: DRY ETCHING METHOD AND METHOD OF
MANUFACTURING SEMICONDUCTOR
APPARATUS

AFTER FINAL RESPONSE AND REQUEST FOR RECONSIDERATION

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the final Office Action dated June 9, 2003
(Paper No. 23), reconsideration of the final rejection of the
claims of the above-identified U.S. patent application is
requested in light of the following remarks.